NF07194US

MICROSCOPE OPTICAL SYSTEM AND MICROSCOPE OBJECTIVE LENS

This application claims the benefit of Japanese Patent applications No. 2002-345967, No. 2003-338495, and No. 2003-359465 which are hereby incorporated by reference.

BACKGROUND OF THE INVENTION

Field of the Invention

The present invention relates to a microscope optical system, and particularly relates to a microscope optical system provided with an intermediate magnification varying part and a microscope objective lens.

Related Background Art

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When cells of an organism, for example, are to be observed, a general process is that a stage is moved under a relatively large field of view at a low magnification so that an object to be observed such as a cancer cell is brought into the field of view and then the magnification is changed to a high magnification so that the object can be observed closely. In the case of examination of cancer cells, cytological examination is generally performed, in which cells or blood sampled from a patient is

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observed by a microscope. In the cytological examination, observation is performed firstly with a relatively large field of view using a microscope objective lens with a magnification of 10x while moving a stage, and if a cell suspected as a cancer cell or the like is discovered, the magnification of the microscope objective lens is switched to 40x for observation with a high resolution. In cytological examination, microscope objective lenses with magnifications of 10x and 40x are typically switched and used.

Such magnification switching is generally performed by switching objective lenses. In the case that objective lenses are switched, an eccentricity in the barrel and a displacement of a focal point position occur in the switching process. Therefore, it is necessary to allow adjustment of those factors by adding an adjusting mechanism in the revolver or by moving the stage.

In addition, in cytological examination, an operation called marking is performed, that is an operation of putting a mark on the cover glass at a position near a suspicious cell.

In order to eliminate need for the abovedescribed adjustment operations or to simplify those
operations, a process of changing the observation
magnification by operating a magnification varying

portion provided on an arm of a microscope has been proposed, for example in Japanese Patent Application Laid-Open No. 2001-166215.

Furthermore, in Japanese Patent Application
Laid-Open No. 9-33818, there is proposed to change
the magnification by a magnification varying
apparatus without switching the microscope objective
lens. In that case, it is preferable that a
microscope objective lens with a magnification of 20x
or so be used. However, the numerical apertures of
microscope objective lenses with a magnification of
20x or so are generally equal to or smaller than 0.5.

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The methods of varying magnification disclosed in the aforementioned prior arts suffer from a problem that in the case that an enlarging magnification varying system is used in combination with an objective lens with a relatively low magnification, high resolution observation is not possible due to the smallness in the numerical aperture of the objective lens. On the other hand, in the case that a reducing magnification varying system is used in combination with an objective lens with a relatively high magnification, there is another problem that aberrations at the periphery of the field of view is deteriorated. In order to eliminate the aforementioned problems, the optical system arrangement in which an image is once formed

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by the light from the objective lens and then the image is enlarged by the magnification varying part has been adopted. However, in the case that an intermediate magnification varying apparatus is used in combination with a microscope, the eye point will be made high and the size of the apparatus will be increased, so that fatigue of the observer tends to be increased when observation is performed for a long period of time. In addition, in that case, the distance between the objective lens and the imaging lens becomes large and the light quantity in the image periphery will be decreased, so that there is a risk that vignetting can occur.

In addition, in the case that an objective lens
with a high magnification is used, there is another
problem that the marking operation is not easy since
the working distance becomes small.

SUMMARY OF THE INVENTION

A first object of the present invention is to provide a microscope optical system in which eccentricity in the barrel and displacement of a focal point position due to switching the objective lenses do not occur upon changing the observation

25 magnification to allow observation of an image with good image quality with the magnification ranging from a relatively low magnification to a relatively high magnification.

In order to attain the aforementioned first object, according to the first invention, there is provided a microscope optical system comprising an objective lens and an intermediate magnification varying part disposed just after the image side of the objective lens.

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In the microscope optical system according to the first invention, it is preferable that the intermediate magnification varying portion include a lens group having a positive refractive power and a lens group having a negative refractive power so that in a high magnification variation state, the lens group having a positive refractive power be disposed just after the image side of the objective lens, while in a low magnification variation state, the lens group having a negative refractive power be disposed just after the image side of the objective lens.

In the microscope optical system according to the first invention, it is preferable that the intermediate magnification varying part be constructed in such a way that its optical system is rotatable with an axis substantially orthogonal to the optical axis being a rotation axis.

In the microscope optical system according to the first invention, it is preferable that the magnification in the high magnification variation

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state be α while the magnification in the low magnification variation state be $1/\alpha$.

In the microscope optical system according to the first invention, it is preferable that the aforementioned magnification α satisfies $1.25 \le \alpha \le 2.5$.

It is preferable that the microscope optical system according to the first invention be provided with a connecting portion on the image side of the intermediate magnification varying part and the microscope optical system can be connected with a body of a microscope by means of the connecting portion.

According to the first invention, an intermediate magnification varying part is provided just after the image side of the objective lens to allow changing of the observation magnification without exchanging the objective lens. Thus, the first invention can provide a microscope optical system in which eccentricity in the barrel and displacement of a focal point position due to switching the objective lenses do not occur upon changing the observation magnification to allow observation of an image with good image quality with the magnification ranging from a relatively low magnification to a relatively high magnification.

A second object of the invention is to provide a microscope objective lens as an infinity optical

system having a large numerical aperture equal to or larger than 0.6 and allowing a large working distance.

In order to attain the aforementioned second object, according to the second invention, there is provided a microscope objective lens comprising, in the following order from the object side, a first lens group and a second lens group, wherein:

the first lens group includes a positive meniscus lens with the concave surface facing the object side and one or more cemented lenses, and has a positive refractive power as a whole;

at least one of the cemented lenses includes a lens made of a material having an Abbe's number equal to or larger than 80; and

the following conditions are satisfied:

 $0.3 \leq \text{wd/f} \leq 0.45$

 $0.6 \leq NA$

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where, f represents the focal length of the microscope objective lens as a whole, wd represents the working distance of the microscope objective lens, and NA represents the numerical aperture of the microscope objective lens.

It is preferable that the microscope objective lens according to the second invention have a magnification of 20x.

In the microscope objective lens according to the second invention, it is preferable that at least

one of the cemented lenses be a cemented lens composed of three lens elements.

In the microscope objective lens according to the second invention, it is preferable that the lens made of a material having an Abbe's number equal to or larger than 80 be made of fluorite.

As per the above, according to the second invention, it is possible to provide a microscope objective lens as an infinity optical system having a large numerical aperture equal to or larger than 0.6 and allowing a large working distance.

BRIEF DESCRIPTION OF THE DRAWINGS

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Figs. 1A and 1B are diagrams showing the lens configuration of a microscope lens system according to a first embodiment of the present invention, wherein Fig. 1A shows the system in the high magnification variation state (2x) and Fig. 1B shows the system in the low magnification variation state (0.5x).

Fig. 2 shows various aberration curves of the microscope optical system according to the first embodiment in the high magnification variation state (2x).

25 Fig. 3 shows various aberration curves of the microscope optical system according to the first embodiment in the low magnification variation state

(0.5x).

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Figs. 4A and 4B are diagrams showing the lens configuration of a microscope lens system according to a second embodiment of the present invention, wherein Fig. 4A shows the system in the high magnification variation state (1.25x) and Fig. 4B shows the system in the low magnification variation state (0.8x).

Figs. 5A and 5B are diagrams showing the lens configuration of a microscope lens system according to a third embodiment of the present invention, wherein Fig. 5A shows the system in the high magnification variation state (1.5x) and Fig. 5B shows the system in the low magnification variation state (0.66x).

Figs. 6A and 6B are diagrams showing the lens configuration of a microscope lens system according to a fourth embodiment of the present invention, wherein Fig. 6A shows the system in the high magnification variation state (2x) and Fig. 6B shows the system in the low magnification variation state (0.5x).

Figs. 7A and 7B are diagrams showing the lens configuration of a microscope lens system according to a fifth embodiment of the present invention, wherein Fig. 7A shows the system in the high magnification variation state (2x) and Fig. 7B shows

the system in the low magnification variation state (0.5x).

Figs. 8A and 8B are diagrams showing the lens configuration of a microscope lens system according to a sixth embodiment of the present invention, wherein Fig. 8A shows the system in the high magnification variation state (2x) and Fig. 8B shows the system in the low magnification variation state (0.5x).

10 Fig. 9 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to a seventh embodiment of the present invention.

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Fig. 10 shows various aberration curves in the seventh embodiment.

Fig. 11 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to an eighth embodiment of the present invention.

20 Fig. 12 shows various aberration curves in the eighth embodiment.

Fig. 13 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to a ninth embodiment of the present invention.

Fig. 14 shows various aberration curves in the ninth embodiment.

Fig. 15 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to a tenth embodiment of the present invention.

Fig. 16 shows various aberration curves in the tenth embodiment.

Fig. 17 is a diagram showing the lens configuration of an imaging lens used in each of the aforementioned embodiments.

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DESCRIPTION OF THE PREFERRED EMBODIMENTS

In the following, embodiments of the present invention will be described with reference to the accompanying drawings.

Embodiments of the microscope optical system according to a first aspect of the present invention will be described in the following.

In an embodiment according to the first aspect of the present invention, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side of the objective lens OL.

The objective lens OL includes a first lens group G1 and a second lens group G2 in the mentioned order from the object side. The first lens group G1 includes a positive meniscus lens L1 with the concave side facing the object side and one or more cemented

lenses (i.e. at least one cemented lens). The first lens group G1 has a positive refracting power as a whole. At least one of the cemented lenses includes a positive lens having a double convex shape made of a material having an Abbe's number equal to or larger than 80. In addition, the objective lens OL satisfies the following conditional expressions:

- (1) $0.3 \le \text{wd/f} \le 0.45$, and
- (2) $0.6 \leq NA$,

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where f represents the focal length of the objective lens OL, wd represents the working distance of the objective lens OL, and NA represents the numerical aperture of the objective lens OL.

In the objective lens of the microscope optical system according to the first aspect of the present invention, the lens surface closest to the object is designed to be concave so that the Petzval sum is made small. Thus, planarity of the image will be ensured.

20 The above-mentioned conditional expression (1) is a condition for defining the working distance wd of the objective lens OL. Values lower than the lower limit value of that conditional expression are not preferable, since with such values the distance between the objective lens OL and the specimen becomes too short and operationality will be deteriorated. Values larger than the upper limit

value of that conditional expression are not preferable, since with such values planarity of the image and chromatic aberration will be deteriorated.

Conditional expression (2) is a condition for determining the numerical aperture NA of the objective lens OL. If the numerical aperture NA is smaller than 0.6, desired resolving powers cannot be obtained.

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As a material having an Abbe's number equal to or larger than 80 for a cemented lens, fluorite is used. A lens made of a material having an Abbe's number smaller than 80 is not preferable since the chromatic aberration will be deteriorated.

The intermediate magnification varying part VL includes a lens group VL1 having a positive refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state, the lens group VL1 having a positive refractive power is disposed adjacent to the image side of the objective lens OL and the lens group VL2 is disposed on the image plane side, so that the synthesized magnification of the microscope optical system is determined as the product of the magnification β of the objective lens OL and the magnification α of the intermediate magnification varying part VL $(\beta \times \alpha)$. On the other hand, in the low magnification variation state, the lens group VL2

having a negative refractive power is disposed adjacent to the image side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane side, so that the synthesized magnification of the microscope optical system is determined as the product of the magnification β of the objective lens OL and the magnification $1/\alpha$ of the intermediate magnification varying part VL $(\beta \times 1/\alpha)$.

The magnification β of the objective lens OL is represented as the ratio of the focal length of the imaging lens used in an actual microscope and the focal length of the microscope objective lens OL (β = (focal length of imaging lens)/(focal length of microscope objective lens OL).

Furthermore, it is preferable that the magnification α of the intermediate magnification varying part VL satisfies the following conditional expression (3):

20 (3) $1.25 \le \alpha \le 2.5$.

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Magnifications lower than the lower limit value of conditional expression (3) are not preferable since with such magnifications the magnification varying effect becomes small and the observation magnification will become too small. Magnifications higher than the upper limit value of conditional expression (3) are not preferably since with such

magnifications the synthesized magnification of the microscope optical system as a whole becomes too high and it will be difficult to correct various aberrations.

5 In the microscope optical system according to the first aspect of the present invention, the intermediate magnification varying part VL is constructed in such a way that it can be rotated with an axis O orthogonal to the optical axis being the 10 rotation axis. The axis O is in the vicinity of a substantially middle point of the on-axis distance of the outermost lens surface (i.e. the lens surface facing the objective lens OL in Fig. 1A) of the lens group VL1 having a positive refractive power and the 15 outermost lens surface (i.e. the lens surface facing the image plane side) of the second lens group VL2.

With this structure, it is possible to arrange the lens group VL1 having a positive refractive power just after the image side of the objective lens OL in the high magnification variation state, and to arrange the lens group VL2 having a negative refractive power just after the image side of the objective lens OL in the low magnification variation state by rotating the optical system of the intermediate magnification varying part VL with the axis O being the rotation axis by 180 degrees.

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By rotating the optical system of the

intermediate magnification varying part VL by 180 degrees, it is possible to switch observation at a high magnification and observation at a low magnification without causing eccentricity in the barrel or displacement of the same focal point.

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On the image plane side of the intermediate magnification varying part VL, there is provided a connecting portion that can be attached to and detached from the body of a microscope. In addition, a connecting portion may also be provided between the objective lens OL and the intermediate magnification varying portion VL so that the objective lens OL can be interchanged. In that case, objective lenses of various magnifications can be used.

In the above described structure, it is preferable that an iris diaphragm S (or an iris) be provided between the objective lens OL and the intermediate magnification varying part VL in the low magnification variation state in order to regulate marginal light fluxes of the objective lens OL.

The structure of the intermediate magnification varying part VL is not limited to the above-described rotatable structure but the same effect cay be realized by constructing the intermediate magnification varying part in such a way that an optical system is selectively inserted on and removed from the optical axis to switch a high magnification

variation state and a low magnification variation state. Alternatively, an optical system having a zooming mechanism may be provided in the intermediate magnification varying part VL.

In the following, embodiments of the microscope optical system according to the present invention will be described.

(First Embodiment)

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Figs. 1A and 1B are diagrams showing the lens configuration of the first embodiment of the microscope optical system according to the present invention. Fig. 1A shows the high magnification variation state (2x) and Fig. 1B shows the low magnification variation state (0.5x).

In figs. 1A and 1B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end the objective lens OL.

The objective lens OL is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object side. The first lens group G1 is composed, in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive

powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

The intermediate magnification varying part VL includes a lens group VL1 having a positive refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 2x, the lens group VL1 having a positive refractive power is disposed just after the image side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation ratio of 0.5x, the intermediate magnification varying part VL is rotated by 180 degrees with the axis O of the magnification varying part being the rotation

axis, so that the lens group VL2 having a negative refractive power is disposed just after the image side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted between the objective lens OL and the intermediate magnification varying part VL.

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Various values associated with the first embodiment are listed in Table 1. In the overall specifications presented in Table 1, f represents the focal length of the objective lens OL at infinity for the d-line (with the wavelength of 587.6nm), NA represents the numerical aperture on the object side, β represents the magnification, wd represents a working distance represented by the distance between the surface of the object and the vertex of the outermost lens surface at the most front side, lpha is the magnification of the intermediate magnification varying part, and the "synthesized magnification" represents the magnification resulting from the magnification of the objective lens OL and the magnification of the intermediate magnification varying part VL. In the lens data, the surface numbers refer to the lens surfaces in the order in which rays pass them, r represents the radius of

curvature of each lens surface, d represents the distance between adjacent lens surfaces, nd represents the refractive index for the d-line, and ν d represents the Abbe's number for the d-line. It is assumed that the refractive index of air is 1.000000, and that value is omitted in the tables.

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For all of the values shown in the following, "mm" (millimeters) is generally used as the unit for the length such as the focal length f, the working distance wd, the radius of curvature r, and the surface distance d, unless otherwise specified. However, the values are not limited to those presented, since optical systems can be proportionally enlarged or reduced in their size without substantially changing their optical performances. In addition, the unit is not limited to millimeters, but other suitable units may also be used. In the low magnification variation state, the lens data of the objective lens portion OL and the value associated with the conditional expression are the same as the lens data and the value associated with the conditional expression in the high magnification variation state, and therefore those data are omitted in the table. The explanations of the signs presented above also apply to the other embodiments that will be described later. addition, in the other embodiments also, the lens

data and the values associated with the conditional expression in the low magnification variation state are the same as those in the high magnification variation state. Such data will be omitted in the other embodiments also.

Table 1 [High Magnification Variation State] (Overall Specifications)

10 f = 10NA = 0.65

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 $\beta = 20$

wd = 4

 $\alpha = 2$

15 Synthesized Magnification = 40

(Lens Data)

	Surfac	e r	đ	nd	νđ	
	Number					
	1	∞	0.17			Cover Glass
20	2	∞	5.1			
	3	-7.800	6.5	1.804	46.6	
	4	-9.4004	0.1			
	5	-22.997	4.2	1.6204	60.3	
	6	-14.498	0.2			
25	7	37.996	4.3	1.569	71.3	
	8	-37.996	1.8	1.6133	44.3	
	9	19.29	8.4	1.4978	82.5	

	10	-23.34	0.1		
	11	24.04	2	1.8466	23.8
	12	13.67	9	1.4978	82.5
	13	-18.46	1.8	1.6133	44.3
5	14	218.7	11.05		
	15	42.003	5.5	1.8052	25.4
	16	-18.48	1.7	1.6133	44.3
	17	13.51	10		
	18	44.99	3	1.4875	70.2
10	19	∞	0.2		
	20	64.65	4	1.6024	60.3
	21	-28.87	2	1.6200	36.3
	22	332.96	20		
	23	-44.99	3.5	1.8052	25.4
15	24	-14.09	2	1.744	44.8
	25	33.01	∞		
	(Valu	ue Associate	ed wit	h Conditiona	al Expression)
	wd/f	E = 0.4			
		·			
20	[Low	Magnificati	lon Va:	riation Stat	te]
-	(Ove	rall Specifi	icatio	ns)	
	f =	= 10			
	NA =	= 0.65			
	β	= 20			
25	wd =	= 4			
	α	= 0.5			

Synthesized Magnification = 10

	(Lens Data)							
	Surfac	e r	đ	nd ·	νđ			
	Number							
	17	13.51	5					
5	18	∞	5		-	Iris	Diaphragm	S
	19	-33.01	2	1.744	44.8			
	20	14.09	3.5	1.8052	25.4			
	21	44.99	20					
	22	-332.96	2	1.6200	36.3			
10	23	28.87	4	1.6024	60.3			
	24	-64.65	0.2					
	25	∞	3	1.4875	70.2			
	26	-44.99	∞				•	

15 Figs. 2 and 3 show curves illustrating aberration characteristics of the microscope optical system according to the first embodiment. Fig. 2 shows the aberration characteristics under the high magnification variation state (2x), and Fig. 3 shows 20 the aberration characteristics under the low magnification variation state (0.5x). In Figs. 2 and 3, NA represents the numerical aperture and Y represents the image height. In the spherical aberration curves, C represents the c-line (with the 25wavelength of 656.3nm), d represents the d-line (with the wavelength of 587.6nm), F represents the F-line (with the wavelength of 486.1nm), and g represents

the g-line (with the wavelength of 435.6nm). In the astigmatism curves, S represents the sagittal image surface for the d-line and M represents the meridional image surface for the d-line. The distortion curves are shown for the d-line. The aberration curves for all the embodiments are based on images formed using an imaging lens that will be described later. Throughout the aberration curves of all of the embodiments, the reference signs the same as those in the aberration curves for this embodiment will be used, and therefore redundant descriptions will be omitted.

As will be apparent from the aberration curves, the aberrations are favorably corrected.

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(Second Embodiment)

Figs 4A and 4B are diagrams showing the lens configuration of the second embodiment of the microscope optical system according to the present invention. Fig. 4A shows the high magnification variation state (1.25x) and Fig. 4B shows the low magnification variation state (0.8x).

In figs. 4A and 4B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end of the objective lens OL.

The objective lens OL is composed of a first lens group Gl having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object The first lens group G1 is composed, in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

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The intermediate magnification varying part VL includes a first lens group VL1 having a positive refractive power and a second lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 1.25x, the lens group VL1 having a positive

refractive power is disposed just after the image side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation state with the magnification variation 5 ratio of 0.8x, the intermediate magnification varying part VL is rotated by 180 degrees with the axis O of the magnification varying part being the rotation axis, so that the lens group VL2 having a negative refractive power is disposed just after the image 10 side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted 15 between the objective lens OL and the intermediate magnification varying part VL.

Various values associated with the second embodiment are listed in Table 2.

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Table 2
[High Magnification Variation State]
(Overall Specifications)

f = 10

25 NA = 0.65

 $\beta = 20$

wd = 4

 α = 1.25 Synthesized Magnification = 25 (Lens Data)

	Surface	e r	đ	nđ	νđ		
5	Number						
	1	∞	0.17			Cover	Glass
•	2	∞	5.1				
	3	-7.800	6.5	1.804	46.6		
	4	-9.4004	0.1				
10	5	-22.997	4.2	1.6204	60.3		
	6	-14.498	0.2				
	7	37.996	4.3	1.569	71.3		
	8	-37.996	1.8	1.6133	44.3		
	9	19.29	8.4	1.4978	82.5		
15	10	-23.34	0.1				
	11	24.04	2 ·	1.8466	23.8		
	12	13.67	9	1.4978	82.5	,	
	13	-18.46	1.8	1.6133	44.3		
	14	218.7	11.05				
20	15	42.003	5.5	1.8052	25.4		
	16	-18.48	1.7	1.6133	44.3		
	17	13.51	10.0				
	18	87.27	4	1.6204	60.1		
	19	-78.17	3	1.7400	28.2		
25	20	-241.38	19				
	21	-134.2	3	1.7847	25.8		
	22	-61.01	2	1.6516	58.5		

(Value Associated with Conditional Expression) wd/f = 0.45 [Low Magnification Variation State] (Overall Specifications) f = 10NA = 0.65 $\beta = 20$ 10 wd = 4 $\alpha = 0.8$ Synthesized Magnification = 16 (Lens Data) νđ đ nd Surface r 15 Number 17 . 13.51 5 18 ∞ 5 Iris Diaphragm S -92.56 2 1.6516 58.5 19 3 1.7847 25.8 20 61.01 20 134.2 19 21 241.38 3 1.7400 28.2 22 1.6204 60.1 3 23 78.17 ∞ -87.27 24

25 (Third Embodiment)

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Figs 5A and 5B are diagrams showing the lens configuration of a third embodiment of the microscope

optical system according to the present invention. Fig. 5A shows the high magnification variation state (1.5x) and Fig. 5B shows the low magnification variation state (0.66x).

In figs. 5A and 5B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end of the objective lens OL.

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The objective lens OL is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object The first lens group G1 is composed, in the side. following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the

following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

The intermediate magnification varying part VL includes a lens group VL1 having a positive 5 refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 1.5x, the lens group VL1 having a positive refractive power is disposed just after the image 10 side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation state with the magnification variation ratio of 0.66x, the intermediate magnification 15 varying part VL is rotated by 180 degrees with the axis O of the magnification varying part being the rotation axis, so that the lens group VL2 having a negative refractive power is disposed just after the image side of the objective lens OL and the lens 20 group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted between the objective lens OL and the 25 intermediate magnification varying part VL.

Various values associated with the third

embodiment are listed in Table 3.

	Table	3				•	
	[High	Magnificat	cion Va	ariation	State]		
5	(Over	all Specifi	cation	ns)			
	f =	10					
	NA =	0.65					
	β =	20					
	wd =	. 4					
10	α =	1.5					
	Synth	nesized Magn	nifica	tion = 30			
•	(Lens	s Data)					
	Surfa	ce r	đ	nđ	νđ		
	Numbe:	r					
15	1	∞	0.17			Cover	Glass
	2	∞	5.1				
	3	-7.800	6.5	1.804	46.6		
	4	-9.4004	0.1				
	5	-22.997	4.2	1.6204	60.3		
20	6	-14.498	0.2				
	7	37.996	4.3	1.569	71.3		
	8	-37.996	1.8	1.6133	44.3		
	9	19.29	8.4	1.4978	82.5		
	10	-23.34	0.1				
25	11	24.04	2	1.8466	23.8		

9

1.8

13.67

-18.46

12

13

1.4978

1.6133

82.5

44.3

```
11.05
      14
            218.7
                         5.5
                               1.8052
                                         25.4
      15
             42.003
                               1.6133
                                         44.3
      16
             -18.48
                         1.7
             13.51
                         10.0
      17
                               1.6204
                                         60.1
 5
      18
             55.63
                         5
                               1.7552
                                         27.6
                         2.5
      19
             -44.24
             -114.23
                         18.5
      20
                               1.7847
                                         25.8
       21
             -69.38
                         3
                                         50.2
             -26.01
                         2
                               1.7199
       22
                         \infty
             56.66
10
       23
       (Value Associated with Conditional Expression)
       wd/f = 0.4
       [Low Magnification Variation State]
 15
       (Overall Specifications)
         f = 10
        NA = 0.65
        \beta = 20
        wd = 4
 20
        \alpha = 0.66
       Synthesized Magnification = 13.2
       (Lens Data)
                                         νd
                          đ
                                nd
       Surface r
25
       Number
             13.51 5
       17
                                            Iris Diaphragm S
             \infty
                          5
       18
```

	19	-56.66	2	1.7199	50.2
	20	26.01	3	1.7847	25.8
	21	69.38	18.5		
	22	114.23	2.5	1.7552	27.6
5	23	44.24	5	1.6204	60.1
	24	-55.63	∞		

(Fourth Embodiment)

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Figs 6A and 6B are diagrams showing the lens configuration of a fourth embodiment of the microscope optical system according to the present invention. Fig. 6A shows the high magnification variation state (2x) and Fig. 6B shows the low magnification variation state (0.5x).

In figs. 6A and 6B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end of the objective lens OL.

The objective lens OL is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object side. The first lens group G1 is composed, in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive

powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape made of fluorite, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape and a negative lens L8 having a double concave shape. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L9 having a double concave shape.

The intermediate magnification varying part VL includes a lens group VL1 having a positive refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 2x, the lens group VL1 having a positive refractive power is disposed just after the image side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation state with the magnification variation ratio of 0.5x, the intermediate magnification varying part VL is rotated by 180 degrees with the axis 0 of the magnification varying part being the rotation

axis, so that the lens group VL2 having a negative refractive power is disposed just after the image side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted between the objective lens OL and the intermediate magnification varying part VL.

Various values associated with the fourth embodiment are listed in Table 4.

Table 4
[High Magnification Variation State]

15 (Overall Specifications)

f = 10

NA = 0.65

 $\beta = 20$

wd = 4

 $20 \quad \alpha = 2$

5

Synthesized Magnification = 40

(Lens Data)

Surface r d nd Vd

Number

25 1 ∞ 0.17 Cover Glass

2 ∞ 5

3 -7.603 7.4 1.804 46.6

```
0.1
            -9.816
      5
            -46.767
                        4.3
                               1.569
                                        71.3
                        0.2
            -17.85
                               1.569
                                         71.3
            41.984
                        4
      7
                                         44.4
5
            -44.998
                        1.8
                               1.6126
      8
                               1.43385
                                         95.25
                                                 fluorite
      9
            20.543
                        8.5
            -20.543
                        0.1
      10
                               1.8052
                                         25.4
      11
            22.761
                         2
                         9
                               1.4978
                                         82.5
      12
            13.612
10
            -18.458
                         1.8
                               1.6126
                                         44.4
      13
            117.68
                         10.9
      14
                         5.3
                               1.6889
                                         31.1
      15
            34.91
                         1.7
                                         56.3
            -15.359
                               1.5688
      16
            12.863
                         10
      17
15
      18
            44.99
                         3
                               1.4875
                                         70.2
      19
             \infty
                         0.2
                                         60.3
            64.65
                         4
                               1.6024
      20
            -28.87
                         2
                               1.6200
                                         36.3
      21
            332.96
                         20
      22
20
      23
            -44.99
                         3.5
                               1.8052
                                         25.4
                                         44.8
            -14.09
                         2
                               1.744
      24
                         \infty
            33.01
      25
      (Value Associated with Conditional Expression)
      wd/f = 0.4
25
      [Low Magnification Variation State]
```

[Low Magnification Variation State]
(Overall Specifications)

f = 10NA = 0.65 $\beta = 20$ wd = 4 $\alpha = 0.5$ 5. Synthesized Magnification = 10 (Lens Data) d nđ ν d r Surface Number 10 12.863 5 17 ∞ Iris Diaphragm S 5 18 -33.01 2 1.744 44.8 19 25.4 20 14.09 3.5 1.8052 44.99 20 21 36.3 15 -332.96 2 1.6200 22 28.87 4 1.6024 60.3 23 24 -64.65 0.2 25. ∞ 3 1.4875 70.2 ∞ -44.99 26

(Fifth Embodiment)

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Figs 7A and 7B are diagrams showing the lens configuration of a fifth embodiment of the microscope optical system according to the present invention.

Fig. 7A shows the high magnification variation state (2x) and Fig. 7B shows the low magnification variation state (0.5x).

In figs. 7A and 7B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end of the objective lens OL.

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The objective lens OL is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object The first lens group G1 is composed, in the side. following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a plano-concave shape and a positive lens L4 having a double convex shape made of fluorite, and a cemented lens composed of a negative meniscus lens L5 with the convex surface facing the object side, a positive lens L6 having a double convex shape and a negative meniscus lens L7 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

The intermediate magnification varying part VL includes a lens group VL1 having a positive

refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 2x, the lens group VL1 having a positive 5 refractive power is disposed just after the image side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation state with the magnification variation ratio of 0.5x, the intermediate magnification varying 10 part VL is rotated by 180 degrees with the axis O of the magnification varying part being the rotation axis, so that the lens group VL2 having a negative refractive power is disposed just after the image 15 side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted 20 between the objective lens OL and the intermediate magnification varying part VL.

Various values associated with the fifth embodiment are listed in Table 5.

25 Table 5
[High Magnification Variation State]
(Overall Specifications)

f = 10

NA = 0.6 $\beta = 20$ wd = 3.55 $\alpha = 2$ Synthesized Magnification = 40 (Lens Data) Surface r đ nd νđ Number 10 ∞ Cover Glass 1 0.17 2 ∞ 4.1 3 -8.301 8.3 1.7727 49.5 4 -10.602 0.1 -56.82 5 4.3 1.4978 82.5 15 -14.983 0.2 1.6126 7 ∞ 2 44.4 8 23.57 7 1.43385 95.25 Fluorite -18.137 0.1 10 25.286 2 1.7552 27.6 20 13.67 7.5 1.4978 82.5 11 12 -20.894 2 1.6126 44.4 16.9 13 -174.644 5 14 42.654 1.7495 35.2 15 -16.113 2 1.5688 56.3 25 12.655 10 16 17 44.99 3 1.4875 70.2 ∞ 0.2 18

	19	64.65	4	1.6024	60.3	
	20	-28.87	2	1.6200	36.3	
	21	332.96	20			
	22	-44.99	3.5	1.8052	25.4	
5	23	-14.09	2	1.744	44.8	
	24	33.01	∞			
	(Va	lue Associa	ted wi	th Condit	ional Expression	1)
	wd/	f = 0.4				
10	[Low	Magnificat	ion Va	riation S	tate]	
	(Ove	rall Specif	ficatio	ns)		
	f	= 10				
	NA	= 0.6				
	β =	= 20				
15	wd	= 3.5				
	α :	= 0.5				
	Synt	hesized Mag	gnifica	tion = 10	1	
	(Len	s Data)				
	Surfa	ace r	đ	nd	νđ	
20	Numbe	er ·				
	16	12.655	5			
	17	∞ .	5		Iris Diaph	ragm S
	18	-33.01	2	1.744	44.8	
	19	14.09	3.5	1.8052	25.4	
25	20	44.99	20			
•	21	-332.96	2	1.6200	36.3	
	22	28.87	4	1.6024	60.3	

23 -64.65 0.2

 $24 \quad \infty \quad 3 \quad 1.4875 \quad 70.2$

25 -44.99 ∞

5 (Sixth Embodiment)

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Figs 8A and 8B are diagrams showing the lens configuration of a sixth embodiment of the microscope optical system according to the present invention. Fig. 8A shows the high magnification variation state (2x) and Fig. 8B shows the low magnification variation state (0.5x).

In Figs. 8A and 8B, the microscope optical system is composed of an objective lens OL and an intermediate magnification varying part VL disposed just after the image side end of the objective lens OL.

The objective lens OL is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object side. The first lens group G1 is composed, in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a

positive lens L5 having a double convex shape made of fluorite, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape made of fluorite and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

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The intermediate magnification varying part VL includes a lens group VL1 having a positive refractive power and a lens group VL2 having a negative refractive power. In the high magnification variation state with the magnification variation ratio of 2x, the lens group VL1 having a positive refractive power is disposed just after the image side of the objective lens OL and the lens group VL2 having a negative refractive power is disposed on the image plane I side. In the low magnification variation state with the magnification variation ratio of 0.5x, the intermediate magnification varying part VL is rotated by 180 degrees with the axis O of the magnification varying part being the rotation axis, so that the lens group VL2 having a negative refractive power is disposed just after the image

side of the objective lens OL and the lens group VL1 having a positive refractive power is disposed on the image plane I side. In addition, in the low magnification variation state, an iris diaphragm S for regulating the marginal light fluxes is inserted between the objective lens OL and the intermediate magnification varying part VL.

Various values associated with the sixth embodiment are listed in Table 6.

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Table 6

[High Magnification Variation State]
(Overall Specifications)

f = 10

15 NA = 0.65

 $\beta = 20$

wd = 3.4

 $\alpha = 2$

Synthesized Magnification = 40

20 (Lens Data)

	Surfac	e r	đ	nd	νd			
	Number	-						
	1	∞	0.17			Cover	Glass	;
	2	∞	4.2					
25	3	-7.603	7.4	1.804	46.6			
	4	-9.816	0.1					
	5	-26.52	4.3	1.569	71.3			

	6	-15.102	0.2			
	7	37	4	1.569	71.3	
	8	-45	1.8	1.6126	44.4	
	9	19.81	8.5	1.43385	95.25	fluorite
5	10	-19.81	0.1			
	11	23.666	2	1.8052	25.4	
	12	14.392	9	1.43385	95.25	fluorite
	13	-18.5	1.8	1.6126	44.4	
	14	-68.199	10.9			
10	15	42.995	5.3	1.6889	31.1	
	16	-15.375	1.7	1.5688	56.3	
	17	13.216	10			
	18	44.99	3	1.4875	70.2	
	19	∞	0.2		•	
15	20	64.65	4	1.6024	60.3	
	21	-28.87	2	1.6200	36.3	
	22	332.96	20			
	23	-44.99	3.5	1.8052	25.4	
	24	-14.09	2	1.744	44.8	
20	25	33.01	∞			
	(Valu	ie Associate	d with	n Conditio	onal Exp	ression)

[Low Magnification Variation State]

25 (Overall Specifications)

f = 10

NA = 0.65

wd/f = 0.34

 $\beta = 20$

wd = 3.4

 $\alpha = 0.5$

Synthesized Magnification = 10

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препо рагал	(]	ìе	ns	Da	ta)
-------------	-----	----	----	----	----	---

	Surfac	e r	đ	nd	νđ
	Number				
	17	13.216	5		
10	18	∞	5		Iris Diaphragm S
	19	-33.01	2	1.744	44.8
	20	14.09	3.5	1.8052	25.4
	21	44.99	20		
	22	-332.96	2	1.6200	36.3
15	23	28.87	4	1.6024	60.3
	24	-64.65	0.2		
	25	∞	3	1.4875	70.2
	26	-44.99	∞		

- In the fourth to sixth embodiments, the intermediate magnification varying part VL may be replaced by the intermediate magnification VL same as those used in the second and third embodiment while attaining the same advantageous effects.
- In the following, embodiments of a microscope objective lens in the form of an infinity optical system according to the second aspect of the present

invention will be described.

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An embodiment of the infinity optical system microscope objective lens according to the second aspect of the present invention includes a first lens group G1 and a second lens group G2 in the mentioned order from the object side. The first lens group Gl includes a positive meniscus lens L1 with the concave side facing the object side and one or more cemented The first lenses (i.e. at least one cemented lens). lens group G1 has a positive refracting power as a whole. At least one of the cemented lenses includes a positive double convex lens made of a material having an Abbe's number equal to or larger than 80. In addition, the infinity optical system microscope objective lens satisfies the following conditional expressions:

- (11) $0.3 \le \text{wd/f} \le 0.45$, and
- (12) $0.6 \leq NA$,

where f represents the focal length of the infinity optical system microscope objective lens as a whole, wd represents the working distance of the infinity optical system microscope objective lens, and NA represents the numerical aperture of the infinity optical system microscope objective lens.

In the infinity optical system microscope objective lens according to the present invention, the lens surface closest to the object is designed to

be concave so that the Petzval sum is made small. Thus, planarity of the image will be ensured.

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The above-mentioned conditional expression (11) is a condition for defining the working distance wd of the infinity optical system microscope objective lens. Values lower than the lower limit value of that conditional expression are not preferable, since with such values the distance between the infinity optical system microscope objective lens and the specimen becomes too short and operationality will be deteriorated. Values larger than the upper limit value of that conditional expression are not preferable, since with such values planarity of the image and chromatic aberration will be deteriorated.

Conditional expression (12) is a condition for determining the numerical aperture NA of the infinity optical system microscope objective lens. If the numerical aperture NA is smaller than 0.6, desired resolving powers cannot be obtained.

In this system, a material having an Abbe's number equal to or larger than 80 is used for at least one of the cemented lenses. A lens made of a material having an Abbe's number smaller than 80 is not preferable since the chromatic aberration will be deteriorated. Materials having Abbe's numbers larger than 80 include fluorite etc.

(Embodiments)

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In the following, embodiments of the infinity optical system microscope objective lens according to the present invention will be described with 5 reference to accompanying drawings. All of the following embodiments are designed as infinity optical systems. When an infinity optical system objective lens according to any one of the embodiments is actually used as an objective lens in 10 a microscope, an imaging lens, for example, as shown in Fig. 17 is to be provided on the image side of the objective lens. The details of the imaging lens will be described later. In the following embodiments, the magnification of the objective lens is 20x. 15 magnification β of an infinity optical system microscope objective lens is represented as the ratio of the focal length of the imaging lens actually used in the microscope and the focal length of the microscope objective lens (namely, β = (focal length 20 of imaging lens)/(focal length of microscope objective lens)).

Fig. 9 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to the seventh embodiment of the present invention. The infinity optical system microscope objective lens is composed of a first lens group Gl having a positive refractive

power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object side. The first lens group G1 is composed, in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape made of fluorite, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the object side, a positive lens L7 having a double convex shape and a negative lens L8 having a double concave shape. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

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Various values associated with the seventh embodiment are listed in Table 7. In the overall specifications presented in Table 7, f represents the focal length of the infinity optical system microscope objective lens at infinity for the d-line (with the wavelength of 587.6nm). Those are the specifications of the microscope objective lens itself independent from any imaging lens. In

addition, NA represents the numerical aperture on the object side, β represents the magnification, and wd represents a working distance represented by the distance between the surface of the object and the vertex of the outermost lens surface at the most 5 front side. In the lens data, the surface numbers refer to the lens surfaces in the order in which rays pass them, r represents the radius of curvature of each lens surface, d represents the distance between 10 adjacent lens surfaces, nd represents the refractive index for the d-line, and Vd represents the Abbe's number for the d-line. It is assumed that the refractive index of air is 1.000000, and that value is omitted in the tables.

15

Table 7
(Overall Specifications)

f = 10

NA = 0.65

 $20 \qquad \beta = 20$

wd = 4

(Lens Data)

Surface r d nd Vd

Number

25 1 ∞ 0.17 Cover Glass

2 ∞ 5

3 -7.603 7.4 1.804 46.6

	4	-9.816	0.1			
	5	-46.767	4.3	1.569	71.3	
	6	-17.85	0.2			
	7	41.984	4	1.569	71.3	
5	8	-44.998	1.8	1.6126	44.4	
	9	20.543	8.5	1.43385	95.25	Fluorite
	10	-20.543	0.1			
	11	22.761	2	1.8052	25.4	
	12	13.612	9	1.4978	82.5	
10	13	-18.458	1.8	1.6126	44.4	
	14	117.68	10.9			
	15	34.91	5.3	1.6889	31.1	
	16	-15.359	1.7	1.5688	56.3	
	17	12.863	∞			

15 (Value Associated with Conditional Expression) wd/f = 0.4

characteristics of the infinity optical system

20 microscope objective lens according to the seventh
embodiment. In the aberration curves, NA represents
the numerical aperture and Y represents the image
height. In the spherical aberration curves, C
represents the c-line (with the wavelength of
656.3nm), d represents the d-line (with the
wavelength of 587.6nm), F represents the F-line (with
the wavelength of 486.1nm), and g represents the g-

line (with the wavelength of 435.6nm). In the astigmatism curves, broken line S represents the sagittal image surface for the d-line and solid line M represents the meridional image surface for the d-line. The distortion curve is shown for the d-line.

As will be apparent from the aberration curves, the aberrations are favorably corrected.

(Eighth Embodiment)

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10 Fig. 11 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to the eighth embodiment of the present invention. The infinity optical system microscope objective lens is composed 15 of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from The first lens group G1 is composed, the object side. in the following order from the object side, of 20 positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens composed of a positive lens L3 having a plano-concave shape and a positive lens L4 having a double convex 25 shape made of fluorite, and a cemented lens composed of a negative meniscus lens L5 with the convex surface facing the object side, a positive lens L6

having a double convex shape and a negative meniscus lens L7 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a positive lens L8 having a double convex shape and a negative lens L9 having a double concave shape.

Various values associated with the eighth embodiment are listed in Table 8.

10

Table 8
(Overall Specifications)

f = 10

NA = 0.6

 $\beta = 20$

wd = 3.5

Surface

Number

(Lens Data)

r

20	1	∞	0.17			Cover Glass
	2	∞	4.1			
	3	-8.301	8.3	1.7727	49.5	
	4	-10.602	0.1			-
	5	-56.82	4.3	1.4978	82.5	
25	6	-14 983	0.2			

nđ

νđ

 $7 \quad \infty \quad 2 \quad 1.6126 \quad 44.4$

đ

8 23.57 7 1.43385 95.25 Fluorite

	9	-18.137	0.1		
•	10	25.286	2	1.7552	27.6
	11	13.67	7.5	1.4978	82.5
	12	-20.894	2	1.6126	44.4
5	13	-174.644	16.9		
	14	42.654	5	1.7495	35.2
	15	-16.113	2	1.5688	56.3
	16	12.655	∞		

(Value Associated with Conditional Expression)

10 wd/f = 0.4

15

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25

Fig. 12 shows curves illustrating aberration characteristics of the infinity optical system microscope objective lens according to the eighth embodiment. As will be apparent from the aberration curves, the aberrations are favorably corrected.

(Ninth Embodiment)

Fig. 13 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to the ninth embodiment of the present invention. The infinity optical system microscope objective lens is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from the object side. The first lens group G1 is composed,

in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens 5 composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape made of fluorite, and a cemented lens composed of a negative meniscus lens L6 with the convex 10 surface facing the object side, a positive lens L7 having a double convex shape made of fluorite and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the 15 following order from the object side, of a positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

Various values associated with the ninth embodiment are listed in Table 9.

20

Table 9
(Overall Specifications)
f = 10

NA = 0.65

(Lens Data)

 $\beta = 20$ wd = 3.4

	Surfac	e r	đ	nđ ·	νd	
	Number					
	1	∞	0.17			Cover Glass
	2	∞	4.2			
5	3	-7.603	7.4	1.804	46.6	
	4	-9.816	0.1			
	5	-26.52	4.3	1.569	71.3	
	6	-15.102	0.2			
	7	37 4	1.569	71.3		
10	8	-45	1.8	1.6126	44.4	
	9	19.81	8.5	1.43385	95.25	Fluorite
	10	-19.81	0.1			-
	11	23.666	2	1.8052	25.4	
	12	14.392	9	1.43385	95.25	Fluorite
15	13	-18.5	1.8	1.6126	44.4	
	14	-68.199	10.9			
	15	42.995	5.3	1.6889	31.1	
	16	-15.375	1.7	1.5688	56.3	
	17	13.216	∞			
20	(Valu	e Associate	d with	Conditio	nal Exp	ression)

Fig. 14 shows curves illustrating aberration characteristics of the infinity optical system

25 microscope objective lens according to the ninth embodiment. As will be apparent from the aberration curves, the aberrations are favorably corrected.

wd/f = 0.34

(Tenth Embodiment)

Fig. 15 is a diagram showing the lens configuration of an infinity optical system microscope objective lens according to the tenth embodiment of the present invention. The infinity optical system microscope objective lens is composed of a first lens group G1 having a positive refractive power and a second lens group G2 having a negative refractive power arranged in the mentioned order from 10 The first lens group Gl is composed, the object side. in the following order from the object side, of positive meniscus lenses L1 and L2 with the concave surfaces facing the object side having positive refractive powers respectively, a cemented lens 15 composed of a positive lens L3 having a double convex shape, a negative lens L4 having a double concave shape and a positive lens L5 having a double convex shape, and a cemented lens composed of a negative meniscus lens L6 with the convex surface facing the 20 object side, a positive lens L7 having a double convex shape and a negative meniscus lens L8 with the concave surface facing the object side. The second lens group G2 is composed of a cemented lens composed, in the following order from the object side, of a 25 positive lens L9 having a double convex shape and a negative lens L10 having a double concave shape.

Various values associated with the tenth embodiment are listed in Table 10.

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'1'' ~	n	le	- 1	0

5 (Overall Specifications)

f = 10

NA = 0.65

 $\beta = 20$

wd = 4

10 (Lens Data)

	Number						
•	1	∞	0.17			Cover	Glass
	2	∞	5.1				
15	3	-7.800	6.5	1.804	46.6		
	4	-9.4004	0.1				
	5	-22.997	4.2	1.6204	60.3		
	6	-14.498	0.2				
20	7	37.996	4.3	1.569	71.3		
	8	-37.996	1.8	1.6133	44.3		
	9	19.29	8.4	1.4978	82.5		
	10	-23.34	0.1				
	11	24.04	2	1.8466	23.8		
	12	13.67	9	1.4978	82.5		
25	13.	-18.46	1.8	1.6133	44.3		
	14	218.7	11.05				
	15	42.003	5.5	1.8052	25.4		

Surface r d nd ν d

16 -18.48 1.7 1.6133 44.3

17 13.51 ∞

(Value Associated with Conditional Expression)
wd/f = 0.4

5

10

15

Fig. 16 shows curves illustrating aberration characteristics of the infinity optical system microscope objective lens according to the tenth embodiment. As will be apparent from the aberration curves, the aberrations are favorably corrected.

Fig. 17 is a diagram showing the lens configuration of an imaging lens used in combination with each of the above-described embodiments.

Various values associated with the imaging lens are listed in Table 11.

Table 11 (Overall Specifications)

f = 200

20 (Lens Data)

	Surf	acé r	đ	nd	νd
	Numb	er			
	1	75.04	5.1	1.6228	57
	2	-75.04	2	1.7495	35.2
25	3	1600.5	7.5		
	4	50.26	5.1	1.6675	42
	5	-84.54	1.8	1.6126	44.4

6 39.91

5

It should be understood that the infinity optical system microscope objective lens according to the present invention is not limited to the above-described embodiments, but changes and modifications can be made to them without departing from the scope of the invention.